

# BEST AVAILABLE COPY

Chamber A pressure setpoint deviation warning. ... more? ... more?

System Wafer Ch A Ch B Ch F Xfer LL A LL B Program Misc A LL B Program Mis

4 Steps for Epi Process Recipe H2 BAKE

SAC ANEAL

	Step 1	Step 2	Step 3	Step 4
Step Name	PURGE	HEAT UP	BAKE	COOL DOWN
Chamber Selection	All	All	All	All
Step End Control	By Time	By Time	By Time	By Time
Maximum Step Time	10 Seconds	45 Seconds	60 Seconds	30 Seconds
Temp Mode : Target	Const Pwr: 20.00 kW	Lower PID: 1000.0 C	Lower PID: 1000.0 C	Const Pwr: 2.00 kW
Temp Rate : PIDs	None : Default	None : Default	None : Default	None : Default
Low A: G In A: L In A:	50 X: 40 X: 40 X:	51 X: 44 X: 44 X:	51 X: 44 X: 44 X:	50 X: 40 X: 40 X:
Power A Ramp	Constant Pwr X	Constant Pwr X	Constant Pwr X	Constant Pwr X
Pressure Mode	Servo to Pressure	Control as Before	Control as Before	Servo to Pressure
Target : Ramp Rate	1240.00 T 20.00 T/s			80.00 T 20.00 T/s
Gas Names and Flows				
Proc/Etch Gas Dest.	Proc:Vent Etch:Vent	Proc:Vent Etch:Vent	Proc:Vent Etch:Vent	Proc:Vent Etch:Vent
Main & Split Purges	M:30.00 S: 5.00w/H2	M:30.00 S: 5.00w/H2	M:20.00 S: 4.00w/H2	M:35.00 S:10.00w/H2
	Charting control	Charting control	Charting control	Charting control
	Expand Step	Expand Step	Expand Step	Expand Step
Step Status/Command	Valid Step / Copy	Valid Step / Copy	Valid Step / Copy	Valid Step / Copy
Directory Header	Delete	Add Before	Add After	Steps > Add After

EXHIBIT

B